

## 290046-2026 - Competition

Switzerland – Laboratory, optical and precision equipments (excl. glasses) – Multitube thermal processing furnace (MTPF) for oxidation and LPCVD at the PSI PICO cleanroom

OJ S 82/2026 28/04/2026

Contract or concession notice – standard regime

Supplies

### 1. Buyer

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#### 1.1. Buyer

Official name: Paul Scherrer Institut (PSI)

Email: [publictenders@psi.ch](mailto:publictenders@psi.ch)

Legal type of the buyer: Body governed by public law

Activity of the contracting authority: Education

### 2. Procedure

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#### 2.1. Procedure

Title: Multitube thermal processing furnace (MTPF) for oxidation and LPCVD at the PSI PICO cleanroom

Description: The equipment to be procured is a multitube thermal processing furnace (MTPF) essential for the deposition of materials for quantum, photonic and x-ray applications of the groups at the LNQ and LXN laboratories and for all PSI cleanroom users. The MTPF should have a horizontal arrangement of the tubes and should be capable to process in one load up to 50 wafers of 200 mm diameter with good within-wafer, wafer-to-wafer and batch-to-batch uniformity. The MTPF should have an automation option allowing to process, at least, 4 wafer batches of 50 wafers in the same or different tubes one after the other without the presence of operator. The MTPF shall be delivered with four 200 mm compatible tubes: – Tube 1: atmospheric thermal dry and wet oxidation (quartz tube up to 1050°C; optional SiC tube up to 1250°C); – Tube 2: LPCVD stoichiometric Si<sub>3</sub>N<sub>4</sub> layers for photonic applications and low-stress Si<sub>N</sub>x layers for membrane fabrication; – Tube 3: LPCVD TEOS-based SiO<sub>2</sub> layers; – Tube 4: LPCVD polycrystalline and amorphous Si. The MTPF shall be installed through the wall, with the loading station on the cleanroom side and the remaining equipment (furnaces, electronic racks, gas cabinets, pumps and related infrastructure) on the gray room side. It shall be capable of 24/7 operation with a guaranteed uptime of at least 90% and a minimum 2-year warranty.

Procedure identifier: d74d9614-7dfe-4e07-a231-9f9897b42fc7

Type of procedure: Open

The procedure is accelerated: no

##### 2.1.1. Purpose

Main nature of the contract: Supplies

Main classification (cpv): 38000000 Laboratory, optical and precision equipments (excl. glasses)

##### 2.1.4. General information

Additional information: Other requirements The bidder must confirm acceptance of the terms of business and the essential requirements in writing. The contractor shall award this contract only to bidders who comply with the conditions stipulated in the tender documents and the

legislation, in particular occupational health and safety regulations, rules on working conditions, equal pay regulations, as well as environmental law, competition law and anti-corruption provisions.

**Legal basis:**

Directive 2014/24/EU

**2.1.6. Grounds for exclusion**

Sources of grounds for exclusion: Procurement Document

## 5. Lot

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**5.1. Lot: LOT-0000**

Title: Multitube thermal processing furnace (MTPF) for oxidation and LPCVD at the PSI PICO cleanroom

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**5.1.1. Purpose**

Main nature of the contract: Supplies

Main classification (cpv): 38000000 Laboratory, optical and precision equipments (excl. glasses)

**Options:**

Description of the options: According specification PSI-PICO-JK67-001 Rev.1.0 chapter 1.5.3

**5.1.2. Place of performance**

Town: Villigen PSI

Postcode: 5232

Country subdivision (NUTS): Aargau (CH033)

Country: Switzerland

**5.1.3. Estimated duration**

Other duration: Unknown

**5.1.4. Renewal**

Maximum renewals: 1

**5.1.6. General information**

**Reserved participation:**



Review organisation: Tribunal administratif fédéral

Information about review deadlines: Instructions on legal remedies In accordance with Article 56 paragraph 1 of the Public Procurement Act (PPA), a written appeal against this decision can be lodged with the Federal Administrative Court, P.O. Box, 9023 St. Gallen, Switzerland, within 20 days of notification. Any appeal is to be submitted in duplicate and must include what is being sought, the grounds for appeal, evidence and the signature of the person lodging the appeal or his or her representative. A copy of this decision and available evidence must be included. The provisions of the Administrative Procedure Act (APA) on legal holidays do not apply in accordance with Article 56 paragraph 2 of the PPA.

Organisation providing additional information about the procurement procedure: Paul Scherrer Institut (PSI)

## 8. Organisations

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### 8.1. ORG-0001

Official name: Paul Scherrer Institut (PSI)

Registration number: 9b458f54-ab31-4dad-a5b8-f1e9a6b16a87

Postal address: Forschungsstrasse 111

Town: Villigen PSI

Postcode: 5232

Country subdivision (NUTS): Aargau (CH033)

Country: Switzerland

Email: [publictenders@psi.ch](mailto:publictenders@psi.ch)

Telephone: +41563102111

Internet address: <https://www.psi.ch>

#### **Roles of this organisation:**

Buyer

Organisation providing additional information about the procurement procedure

### 8.1. ORG-0002

Official name: Tribunal administratif fédéral

Registration number: BVGER

Postal address: Postfach

Town: St. Gallen

Postcode: 9023

Country subdivision (NUTS): St. Gallen (CH055)

Country: Switzerland

Email: [info@bvger.admin.ch](mailto:info@bvger.admin.ch)

Telephone: +41584652626

Internet address: <https://www.bvger.ch>

#### **Roles of this organisation:**

Review organisation

### 8.1. ORG-0003

Official name: Simap.ch

Registration number: CH001

Postal address: Holzikofenweg 36

Town: Bern

Postcode: 3003

Country subdivision (NUTS): Bern / Berne (CH021)

Country: Switzerland  
Email: [support@simap.ch](mailto:support@simap.ch)  
Telephone: +41584646388  
Internet address: <https://www.simap.ch>  
**Roles of this organisation:**  
TED eSender

## Notice information

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Notice identifier/version: 324bdbea-b2b3-449e-b67c-ad6f1294fd5c - 01  
Form type: Competition  
Notice type: Contract or concession notice – standard regime  
Notice subtype: 16  
Notice dispatch date: 25/04/2026 02:25:51 (UTC+02:00) Eastern European Time, Central European Summer Time  
Languages in which this notice is officially available: English, German, French  
Notice publication number: 290046-2026  
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